

The Conference Theme

*“What's the 2nd Mainstream of Device Technology?”
- For Successive Evolution of Electron Devices-*

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Tutorials (in Japanese)

9:30-10:30 MTJ based non volatile SAM and low power non volatile logic-in-memory architecture
Tetsuo Endoh (Tohoku University)

10:40-11:40 The Future of OLED: Light Source and Display
Junji Kido (Yamagata University)

Opening

13:00-13:10 Opening Remarks by Yoichi Akasaka (Osaka University)

Keynote Speeches

13:10-14:00

K-1 (p.20) Junctionless Transistors
Jean-Pierre Colinge (TSMC)

14:00-14:50

K-2 (p.22) Recent Progress of Germanium MOSFETs
Akira Toriumi (The University of Tokyo)

Short Break (14:50-15:00)

15:00-15:50

K-3 (p.24) Toward Full Fluctuation Analysis of Small FETs
Yiming Li and Hui-Wen Cheng (NCTU)

15:50-16:40

K-4 (p.26) Highly reliable low power Solid-State Drives (SSDs)
Ken Takeuchi (The University of Tokyo)

Break (16:40-17:00)

Technical Session - EDS (A) (Emerging Devices)

17:00-17:20

- A-1 (p.38)** Observation of Conductive Filament Formation in an Organic Non-volatile Memory Resistor Device
Toan Thanh Dao^{1,2}, Thu Viet Tran¹, Koichi Higashimine¹, Hiromasa Okada³, Derrick Mott¹, Shinya Maenosono¹ and Hideyuki Murata¹
(¹JAIST, ²University of Transport and Communications, ³International Test & Engineering Services Co., Ltd.)

17:20-17:40

- A-2 (p.40)** Luminescence Properties of Ge-Implanted SiO₂ Layer on Si Substrate for Blue-UV Light Source with Low-Voltage Drive
Nobutoshi Arai¹, Go Miyagawa², Shohei Kinoshita², Masatomi Harada¹, Hiroshi Tsuji², Hiroshi Kotaki¹, Akira Takahashi¹ and Yasuhito Gotoh² (¹SHARP CORPORATION, ²Kyoto University)

17:40-18:00

- A-3 (p.42)** Frequency mixing with a tetrode vacuum transistor
Yoshiki Yasutomo, Yasuhito Gotoh, Wataru Ohue and Hiroshi Tsuji (Kyoto University)

18:00-18:20

- A-4 (p.44)** Graphene-based electro-optical modulator: concept and analysis
Victor Ryzhii¹, Akira Satou¹, Taiichi Otsuji¹, Maxim Ryzhii², Nadezhda Ryabova², Stanislav O. Yurchenko³ and Michael S. Shur⁴ (¹Tohoku University, ²University of Aizu, ³Bauman Moscow State Technical University, ⁴Rensselaer Polytechnic Institute)

Special Invited Session - SSCS

9:30-10:20

I-1 (p.30) Essence and Technology Direction of ADC Design
Akira Matsuzawa (Tokyo Institute of Technology)

10:20-11:10

I-2 (p.32) Implantable CMOS Biomedical Devices
Jun Ohta (Nara Institute of Science and Technology)

Lunch (11:10-13:00)

Technical Session - SSCS

13:00-13:20

S-1 (p.70) Co-evaluation of Power Supply Noise of CMOS Microprocessor using On-Board Magnetic Probing and On-Chip Waveform Capturing Techniques
Yuta Sasaki¹, Kumpei Yoshikawa¹, Kouji Ichikawa² and Makoto Nagata¹ (¹Kobe University, ²DENSO CORPORATION)

13:20-13:40

S-2 (p.72) Circuit Characteristic Analysis Considering NBTI and PBTI-Induced Delay Degradation
Michitarou Yabuuchi¹ and Kazutoshi Kobayashi^{1,2}
(¹Kyoto Institute of Technology, ²CREST)

13:40-14:00

S-3 (p.74) Low Power and More Accurate Temperature Sensor with an Integrated Dual Slope AD Converter
Takeshi Nagahisa, Shinichi Kubota and Hirobumi Watanabe
(Ricoh Company, Ltd.)

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Poster Session

Short Presentation – 2min. each (5/10, 14:20-16:20)

- PA-01 (p.78)** Transport Properties of Post-Stressed sol-gel-Based TiO₂ Films
Yusuke Kondo, Susumu Tamura and Yasuhisa Omura
(Kansai University)
- PA-02 (p.80)** TEM observation of directly bonded interface between Si and SiC
Takamasa Kurumi, Ryosuke Araki, Hiroyuki Kinoshita and Masahiro Yoshimoto (Kyoto Institute of Technology)
- PA-03 (p.82)** Photoluminescence study on recrystallization of ultra-shallow junction towards in-line measurements
Gota Murai¹, Masashi Okutani¹, Hiroki Saikusa¹, Masahiro Yoshimoto¹ and Woo Sik Yoo²
(¹Kyoto Institute of Technology, ²WaferMasters, Inc)
- PA-04 (p.84)** Evaluation of morphology and crystal structure of Si nanowires prepared by single-step metal assisted etching
Takuya Yamaguchi, Tomohiro Shimizu, Fumihiro Inoue, Choung Wang, Mitsuru Inada, Tadashi Saitoh and Shoso Shingubara (Kansai University)
- PA-05 (p.86)** Electroless Deposition of Barrier and Seed Layers for Via Last Cu-TSV Metalization
Fumihiro Inoue, Tomohiro Shimizu, Ryohei Arima, Hiroshi Miyake and Shoso Shingubara (Kansai University)
- PA-06 (p.88)** Ellipsoidal Band Structure Effects on Current-Voltage Characteristics in Silicon Nanowire Transistors
Yi Yan and Nobuya Mori (Osaka University)

- PA-07 (p.90)** An Estimation of the Inversion Charge Influenced by Quantum Effect for Sub-20nm MOSFETs
Masahiro Yamamoto, Akira Hiroki and Jong Chul Yoon
(Kyoto Institute of Technology)
- PA-08 (p.92)** Structure Dependence of Reduced Saturation Current Influenced by Source and Drain Resistances for 17 nm MOSFETs
Jong Chul Yoon, Akira Hiroki and Kazutoshi Kobayashi
(Kyoto Institute of Technology)
- PA-09 (p.94)** Improvement of Drain Leakage Current Characteristics in Metal-Oxide-Semiconductor-Field-Effect-Transistor by Asymmetric Source-Drain Structure
Byoung-seon Choi, Hyunae Park, Dongsoo Kim and Byoung-deog Choi (Sungkyunkwan University)
- PA-10 (p.96)** Observation of Direct Tunneling Conduction for TDTFT in High Temperatures
Takahiro Kobayashi¹, Naoto Matsuo¹, Akira Heya¹, Yasuhisa Omura² and Shin Yokoyama³
(¹University of Hyogo, ²Kansai University, ³Hiroshima University)
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(¹University of Hyogo, ²Kyusyu University)
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- PB-03 (p.104)** Analysis of electron transport in AlGa_N based on empirical pseudopotential method
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Zi-Hao Wang¹, Ping-Chuan Chang¹, Kai-Hsuan Lee² and Shoou-Jinn Chang²
(¹Kun Shan University, ²National Cheng Kung University)
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(¹Osaka University, ²REST)
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(Osaka Institute of Technology)
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(¹Osaka Institute of Technology, ²Osaka University)
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(¹National Chiao-Tung University, ²Chung Hua University, ³I-Shou University and ⁴Tse-An Clinic)
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(¹Nara Institute of Science and Technology, ²CREST)

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Makito Haruta¹, Takuma Kobayashi^{1,2}, Chikara Kitsumoto¹, Toshihiko Noda^{1,2}, Kiyotaka Sasagawa^{1,2}, Takashi Tokuda^{1,2} and Jun Ohta^{1,2} (¹Nara Institute of Science and Technology, ²CREST)
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Yuri Ohara¹, Prinya Lorchirachoonkul¹, Alberto Ortiz Artero², Toshinori Shimanouchi³, Kaoru Yamashita¹ and Minoru Noda¹
(¹Kyoto Institute of Technology, ²Universitat Politècnica de Catalunya, ³Osaka University)

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Takeshi Ohmi and Yoshinari Kamakura (Osaka University)

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Hiroyuki Nakashima, Mitsuru Inada and Tadashi Saitoh
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Shintaro Otsuka¹, Tomohiro Shimizu², Shoso Shingubara², Satoshi Kurumi¹, Kaoru Suzuki¹, Nobuyuki Iwata¹, Tadataka Watanabe¹, Yoshiki Takano¹ and Kouichi Takase¹
(¹Nihon University, ²Kansai University)

PS-01 (p.156) 80GHz 12.2mW p-MOS Cross-Coupled CMOS LC-Oscillator

Shunsuke Tanimori, Mizuki Motoyoshi, Kosuke Katayama, Kyoya Takano and Minoru Fujishima (Hiroshima University)

PS-02 (p.158) 118GHz CMOS Amplifier with Group Delay Variation of 11.2ps and 3dB Bandwidth of 20.4GHz

Akihiko Orii, Mizuki Motoyoshi, Kyoya Takano, Kousuke Katayama and Minoru Fujishima (Hiroshima University)

PS-03 (p.160) Maximizing Transducer Gain per Power Dissipation on 100 GHz CMOS Six Stage Amplifier

Masafumi Suizu, Kosuke Katayama, Mizuki Motoyoshi, Kyoya Takano and Minoru Fujishima
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Chu-Feng Chen¹, Chiung-Hui Lai¹, Kow-Ming Chang^{1,3}, Cheng-Ting Hsieh¹, Chin-Ning Wu¹, Yu-Bin Wang¹, Chung-Hsien Liu¹ and Kuo-Chin Chang⁴

(¹National Chiao-Tung University, ²Chung Hua University, ³I-Shou University and ⁴Tse-An Clinic)

PS-05 (p.164) Modeling and Analysis of Interference between Phase-Locked Loops

Junki Mizuno¹, Tsutomu Yoshimura¹, Syuhei Iwade¹, Hiroshi Makino¹ and Yoshio Matsuda²

(¹Osaka Institute of Technology, ²Kanazawa University)

PS-06 (p.166) Process variation compensation with effective gate-width tuning for low-voltage CMOS digital circuits

Yasushi Kishiwada, Shun Ueda, Yusuke Miyawaki and Toshimasa Matsuoka (Osaka University)

Poster Session

Cheese and Wine (5/10, 16:20-18:20)

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Technical Session - EDS (B) (Silicon Devices and Related)

10:30-10:50

- B-1 (p.48)** Effect of High-pressure Deuterium Oxide Annealing on Al₂O₃ Deposited by Plasma-assisted Atomic Layer Deposition at Low Temperature
Koji Yoshitsugu¹, Kosuke Ohara¹, Nozomu Hattori³, Masahiro Horita^{1,2}, Yasuaki Ishikawa^{1,2} and Yukiharu Uraoka^{1,2}
(¹Nara Institute of Science and Technology, ²CREST and ³Mitsui Engineering & Shipbuilding Co.,Ltd)

10:50-11:10

- B-2 (p.50)** Nanodot-type Floating Gate Memory with High-density Nanodot Array Formed Utilizing Listeria Ferritin
Hiroki Kamitake^{1,2}, Kosuke Ohara¹, Mutsunori Uenuma^{1,2}, Bin Zheng^{1,2}, Yasuaki Ishikawa^{1,2}, Ichiro Yamashita^{1,2,3} and Yukiharu Uraoka^{1,2} (¹Nara Institute of Science and Technology, ²CREST and ³Panasonic Corp.)

11:10-11:30

- B-3 (p.52)** Mechanical strain altered gate and substrate currents in n and p-channel MOSFETs
Wangran Wu, Jiabao Sun and Yi Zhao (Nanjing University)

Lunch (11:30-13:30)

Technical Session - EDS (C) (Compound Semiconductor Device)

13:30-13:50

- C-1 (p.56)** Fundamental Study on Junction Termination Structures for Ultrahigh-Voltage SiC PiN Diodes
Hiroki Niwa, Jun Suda and Tsunenobu Kimoto (Kyoto University)

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C-2 (p.58) Analysis of Electron Traps in SiO₂/IGZO Interface by Cyclic Capacitance-Voltage Method

Yoshihiro Ueoka, Mami Fujii, Haruka Yamazaki, Masahiro Horita, Yasuaki Ishikawa and Yukiharu Uraoka (Nara Institute of Science and Technology)

14:10-14:30

C-3 (p.60) Dependence of Semiconductor Nanoparticle Size on Spray Condition in Electro-Spray Deposition Method

Takahiro Doe^{1,2}, Shinji Araki^{1,2}, Masahiro Horita^{1,2}, Takashi Nishida^{1,2}, Yasuaki Ishikawa^{1,2} and Yukiharu Uraoka^{1,2} (¹Nara Institute of Science and Technology, ²CREST)

14:30-14:50

C-4 (p.62) Highly reliable a-InGaZnO thin film transistors with new SiN_x gate insulators

Haruka Yamazaki¹, Mami Fujii¹, Yoshihiro Ueoka¹, Yasuaki Ishikawa¹, Masaki Fujiwara², Eiji Takahashi² and Yukiharu Uraoka¹ (¹Nara Institute of Science and Technology, ²Nissin Electric Co., Ltd.)

14:50-15:10

C-5 (p.64) Fabrication of Nano-patterns Using Quick Gel-nanoimprint Process

Shinji Araki¹, Min Zhang¹, Takahiro Doe¹, Li Lu¹, Masahiro Horita^{1,2}, Takashi Nishida^{1,2}, Yasuaki Ishikawa^{1,2} and Yukiharu Uraoka^{1,2} (¹Nara Institute of Science and Technology, ²CREST)

15:10-15:30

C-6 (p.66) High-Resistance ZrN Thin Film Resistor For Small and Low-cost MMIC Switch

Masahiro Shibata, Hiroaki Tokuya, Satoshi Yamamoto, Tsunekazu Saimei, Takatoshi Kato and Tadao Fukura (Murata Manufacturing Co., Ltd.)

Break (15:30-15:50)

Special Invited Session - EDS

15:50-16:40

I-3 (p.34) New Communication Paradigm by Compelling Wireless Technology

Yuichi Kado (Kyoto Institute of Technology)

Break (16:40-16:50)

16:50-17:10 Award Presentation: Yasuhisa Omura (Kansai University)

17:10-17:20 Closing Remark: Yasuhisa Omura (Kansai University)